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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants : Eiju KOMURO et al.

Group Art Unit : 1765

Appl. No. : 10/811,812

Examiner : M. DAHIMENE

Filed : March 30, 2004

Confirmation No. : 2851

For : METHOD OF MANUFACTURING A PIEZOELECTRIC THIN FILM RESONATOR, MANUFACTURING APPARATUS FOR A PIEZOELECTRIC THIN FILM RESONATOR, PIEZOELECTRIC THIN FILM RESONATOR, AND ELECTRONIC COMPONENT

COMMENTS ON STATEMENT OF REASONS FOR ALLOWANCE

Commissioner for Patents
U.S. Patent and Trademark Office
Customer Service Window, Mail Stop Issue Fee
Randolph Building
401 Dulany Street
Alexandria, VA 22314

Sir :

In response to the Notice of Allowability mailed by the U.S. Patent and Trademark Office on April 10, 2007, and to the Statement of Reasons for Allowance attached thereto, Applicants wish to clarify the record with respect to the basis for the patentability of claims in the present application. In this regard, while Applicants do not disagree with the Examiner's indication of allowability, Applicants submit that each of the claims in the present application recite a combination of features, and that the basis for patentability of each of these claims is based on the combination of features recited therein.

Should there be any questions, the Examiner is invited to contact the undersigned at the below-listed telephone number.

Respectfully Submitted,
Eiju KOMURO et al.

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May 30, 2007
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